

10/539875**JC06 Rec'd PCT/PTO, 17 JUN 2005**

""Express Mail" mailing label number: EV 653877459 US

Date of Deposit: June 17, 2005Case No. 9905/29
Client No. BIF023249/US**UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:)	
)	
PERRET et al.)	
)	Examiner:
Serial No.: Not Yet Assigned)	Not Yet Assigned
)	
Filing Date: Herewith)	Group Art Unit:
)	Not Yet Assigned
For: NANO-IMPRINT LITHOGRAPHY)	
METHOD INVOLVING SUBSTRATE)	
PRESSING)	
)	

INFORMATION DISCLOSURE STATEMENTCommissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98, and more particularly in accordance with 37 C.F.R. §1.97(b), Applicants hereby cite the following references:

No.	Date of Publication	Patentee/Applicant/Country
US 2002/0170880 A1	11/21/2002	Chen
5,772,905	06/30/1998	Chou
WO 01/79933 A1	10/25/2001	EPO
Lebib et al., "Tri-Layer Systems for Nanoimprint Lithography With an Improved Process Latitude ", Microelectronic Engineering 53 (2000), pp. 175-178.		

For the Examiner's convenience, Applicants are enclosing Form PTO-1449 (one sheet), and as each of the listed references is in English, no further commentary is believed to be necessary, 37 C.F.R §1.98(a)(3). Applicant respectfully requests the Examiner's consideration of the above references and entry thereof into the record of this application.

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Attorney Docket No. 9905/29 (BIF023249/US)

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Also enclosed is a copy of the International Search Report issued on May 17, 2004 for corresponding PCT Application No. PCT/FR03/03866 of the above-identified application.

By submitting this Statement, Applicants are attempting to fully comply with the duty of candor and good faith mandated by 37 C.F.R. §1.56. As such, this Statement is not intended to constitute an admission that any of the enclosed references, or other information referred to therein, constitutes "prior art" or is otherwise "material to patentability," as that phrase is defined in 37 C.F.R. §1.56(a).

Applicants have calculated no fee to be due in connection with the filing of this Statement. However, the Director is authorized to charge any fee deficiency associated with the filing of this Statement to a deposit account, as authorized in the Transmittal accompanying this Statement.

Respectfully submitted,

June 17, 2005


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FORM PTO-1449	SERIAL NO. Not Yet Assigned	CASE NO. 9905/29 (BIF023249/US)
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE Herewith	GROUP ART UNIT Not Yet Assigned
APPLICANTS: PERRET et al.		

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER <small>Number-Kind Code (if known)</small>	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
	A1	US 2002/0170880 A1	11/21/2002	Chen		
	A2	5,772,905	06/30/1998	Chou		

FOREIGN PATENT DOCUMENT

EXAMINER INITIAL		DOCUMENT NUMBER <small>Number-Kind Code (if known)</small>	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
	A3	WO 01/79933 A1	10/25/2001	EPO		

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS <small>(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.</small>	
	A4	Lebib et al., "Tri-Layer Systems for Nanoimprint Lithography With an Improved Process Latitude ", Microelectronic Engineering 53 (2000), pp. 175-178.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.